

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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	July 21, 2003
	Luan C. Trar
	Micron Technology, Inc.
	2812
•	Kennedy, Jennifer M.
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	Methods of Forming Semiconductor Constructions

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References -See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56. Copies of the cited art are included with the exception of U.S. patents and published U.S. applications (1276 OG 55). No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Jennifer J. Taylor, Ph.D. Reg. No. 48,711

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	AR								
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